

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

<i>In re</i> Application of:	Hai Cong, et al.	:	Confirmation No.:	4993
Serial No.:	10/767,292	:	Art Unit:	2812
Filed:	1/29/2004	:	Examiner:	Mohsen Ahmadi
For:	A NOVEL METHOD TO CONTROL DUAL DAMASCENE TRENCH ETCH PROFILE AND TRENCH DEPTH UNIFORMITY			

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Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

**RESPONSE AFTER FINAL REJECTION
UNDER 37 C.F.R. §1.116**

Sir/Madam:

The following Remarks are submitted under 37 C.F.R. §1.116 in response to the Final Office Action mailed December 19, 2006. After this introductory section, there are Remarks starting on a separate page.

Reconsideration of the rejections is respectfully requested.